



Applicant(s):

Yoo, Woo Sik

Assignee:

WaferMasters Incorporated

Title:

Method for H₂ Recycling In Semiconductor Processing System

Serial No.:

09/828,518

Filing Date:

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Examiner:

To be assigned

Group Art Unit:

To be assigned

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M-8608 US

Newport Beach, California May 24, 2001

COMMISSIONER FOR PATENTS Washington, D. C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

- 1. an admission that the documents are necessarily prior art with respect to the instant invention;
 - 2. a representation that a search has been made, other than as described above; or
- 3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

EXPRESS MAIL LABEL NO:

EL 849 434 738 US

Respectfully submitted,

Attorney for Applicant(s)

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